

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

Yuichi MATSUI

Appln. No.:

Filed: Herewith

For: SEMICONDUCTOR DEVICE AND MANUFACTURING METHOD THEREOF

\* \* \*

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. § 1.56, and without any assertion as to materiality or prior art effect, the documents listed on the attached Form PTO-1449 are hereby cited.

Documents AJ-AO and BJ-BN on the attached List are cited in the specification, on pages 2-3, and their relevance is indicated therein.

Respectfully submitted,

NHS:lmb

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(703) 903-9000

April 22, 2004

FORM PTO-1449		Atty. Docket No. <b>XA-10070</b>	Appln. No.
<u>LIST OF DOCUMENTS CITED BY APPLICANT</u>		Applicant <b>Yuichi MATSUI</b>	
		Filing Date <b>HEREWITH</b>	Group

## U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA	5,622,888	4/22/97	Sekine et al.	438	398	
	AB	6,235,572	5/22/01	Kunitomo et al.	438	240	
	AC	6,243,255	6/5/01	Kuge et al.	361	528	
	AD	2003/0011022	1/16/03	Manabe	257	314	
	AE	6,576,928	6/10/03	Hiratani et al.	257	68	
	AF	6,673,461	1/6/04	Chazono et al.	428	469	
	AG	5,970,337	10/19/99	Nishioka	438	240	
	AH	2003-0151083	8/14/03	Matsui et al.	257	310	
	AI						

## FOREIGN PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AJ	8-139288	5/31/96	JAPAN			abstract
	AK	2000-12796	1/14/00	JAPAN			abstract
	AL	2000-82639	3/21/00	JAPAN			abstract
	AM	2002-164516	6/7/02	JAPAN			abstract
	AN	2003-243534	8/29/03	JAPAN			abstract
	AO	2001-77108	3/23/01	JAPAN			abstract

## OTHER (including author, title, date, pertinent pages, etc.)

	AP	Rosenfeld, D. et al., "Structural and morphological characterization of Nb <sub>2</sub> O <sub>5</sub> thin films deposited by reactive sputtering", <u>American Vacuum Society</u> , 1994, pp. 135-139.
	AQ	
	AR	

Examiner	Date Considered
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.

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<b>U. S. PATENT DOCUMENTS</b>							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	BA						
	BB						
	BC						
	BD						
	BE						
	BF						
	BG						
	BH						
	BI						
<b>FOREIGN PATENT DOCUMENTS</b>							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	BJ	<b>5-345663</b>	<b>12/27/93</b>	<b>JAPAN</b>			<b>abstract</b>
	BK	<b>10-12043</b>	<b>1/16/98</b>	<b>JAPAN</b>			<b>abstract</b>
	BL	<b>2001-284158</b>	<b>10/12/01</b>	<b>JAPAN</b>			<b>abstract</b>
	BM	<b>8-31951</b>	<b>2/2/96</b>	<b>JAPAN</b>			<b>abstract</b>
	BN	<b>11-330415</b>	<b>11/30/99</b>	<b>JAPAN</b>			<b>abstract</b>
	BO						
<b>OTHER</b> (including author, title, date, pertinent pages, etc.)							
	BP						
	BQ						
	BR						
Examiner				Date Considered			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							